

Figure 1. (a) Optical image of fabricated Nb/  $\text{Hf}_{0.5}\text{Zr}_{0.5}\text{O}_2$ / NbN FTJs with top Nb and HZO patterned to realize isolated MFM capacitors with diameters varied from  $74 \mu\text{m}$  to  $117 \mu\text{m}$ . (b) Cross sectional schematic highlighting the thickness of individual FTJ layers.

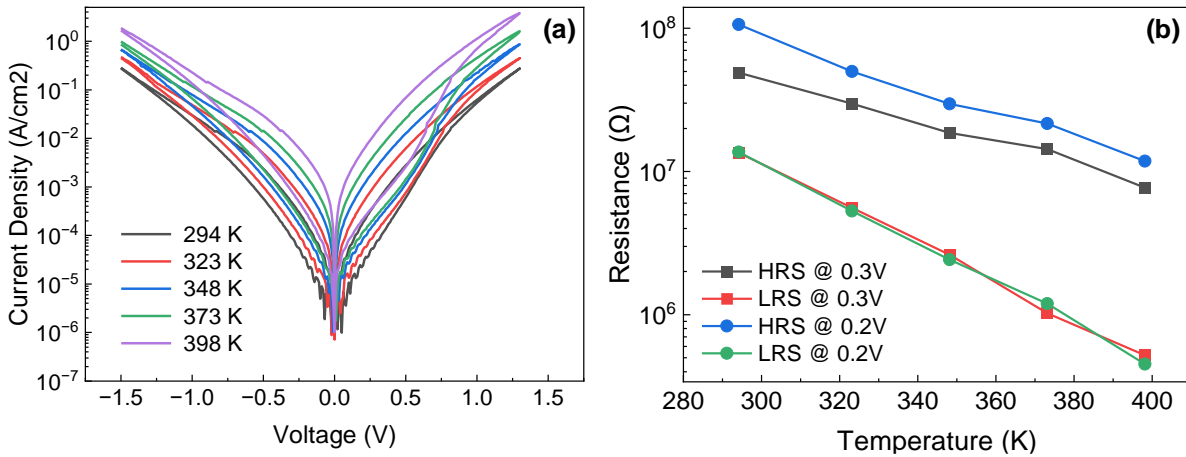


Figure 2. (a) Current density of a  $100 \mu\text{m}$  diameter ( $7,854 \mu^2$  area) Nb/  $\text{Hf}_{0.5}\text{Zr}_{0.5}\text{O}_2$ / NbN FTJ per chuck temperature with drive voltage swept from  $-1.5\text{V}$  to  $1.3\text{V}$ . (b) High resistance state (HRS) and low resistance state (LRS) resistances for the same device read at  $0.2\text{V}$  and  $0.3\text{V}$  from  $294\text{K}$  to  $398\text{K}$ . Of note is a negative linear trend with temperature on a semi-log plot, alluding that conduction in HZO FTJs is exponentially

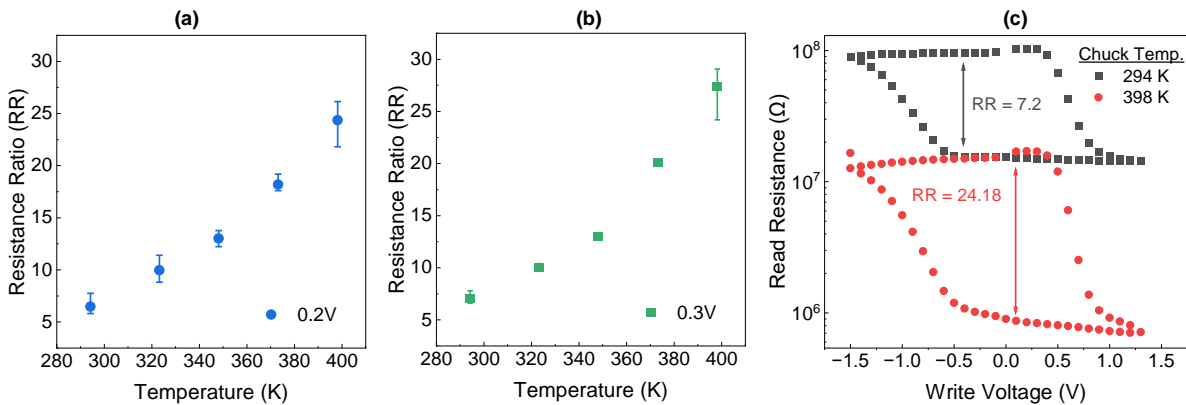


Figure 3. Average and outlier resistance ratios (RRs) across temperature for  $74, 86, 100,$  and  $117 \mu\text{m}$  diameter HZO FTJs, calculated at (a)  $0.2\text{V}$  and (b)  $0.3\text{V}$ . (c) Pulsed hysteresis measurement for a  $7,697 \mu^2$  area device at  $294\text{K}$  and  $398\text{K}$ . Device resistance is read at  $0.2\text{V}$  and a pulse width of  $100\text{ms}$ , following a write pulse progressing from  $-1.5\text{V}$  to  $1.3\text{V}$  and back with  $100\text{mV}$  step and  $100\text{ms}$  pulse width.